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ISCHUB is trying to help the students . Pradeep's Chemistry Class 12 pdf Free Download; Pradeep's Chemistry Class 12 book Free Download; Pradeep's Chemistry Class 12 e-book Free Download. The present invention relates to a method for forming a substrate for a piezoelectric device with a high aspect ratio using an etching technique, and more particularly, to a method for forming a substrate for a piezoelectric device with a high aspect ratio using an etching technique, in which an upper surface of a lower electrode is formed by etching a multilayer structure formed on a substrate. Generally, in a substrate for a piezoelectric device, such as a piezoelectric device (PZT) or a thin-film magnetic element, a lower electrode is formed on a substrate and an upper electrode is formed on the lower electrode. The upper electrode is formed through an etching technique using an etchant having an etch selectivity to a material of the lower electrode and the upper electrode. The lower electrode is formed by performing an etching technique using a dry etching method, such as a reactive ion etching (RIE) method, a sputtering method, or a laser ablation method, using a material of a semiconductor substrate, such as Si

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